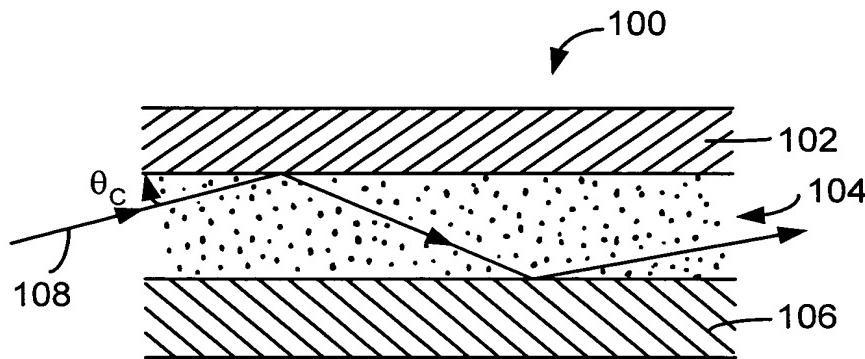
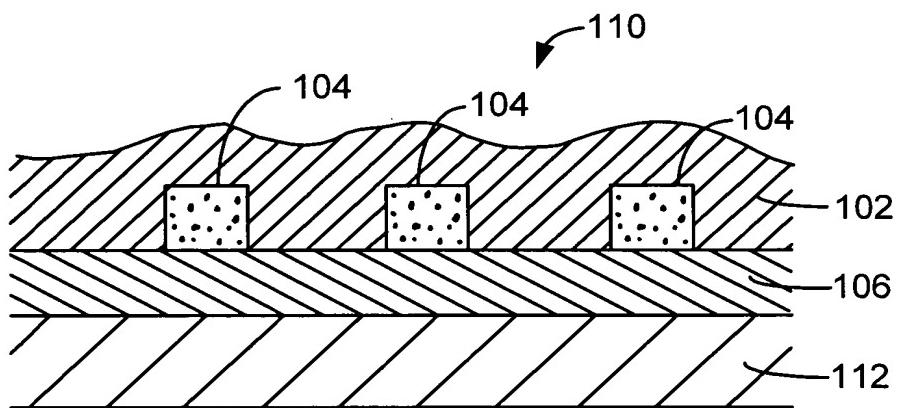




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**FIG. 1A****FIG. 1B**

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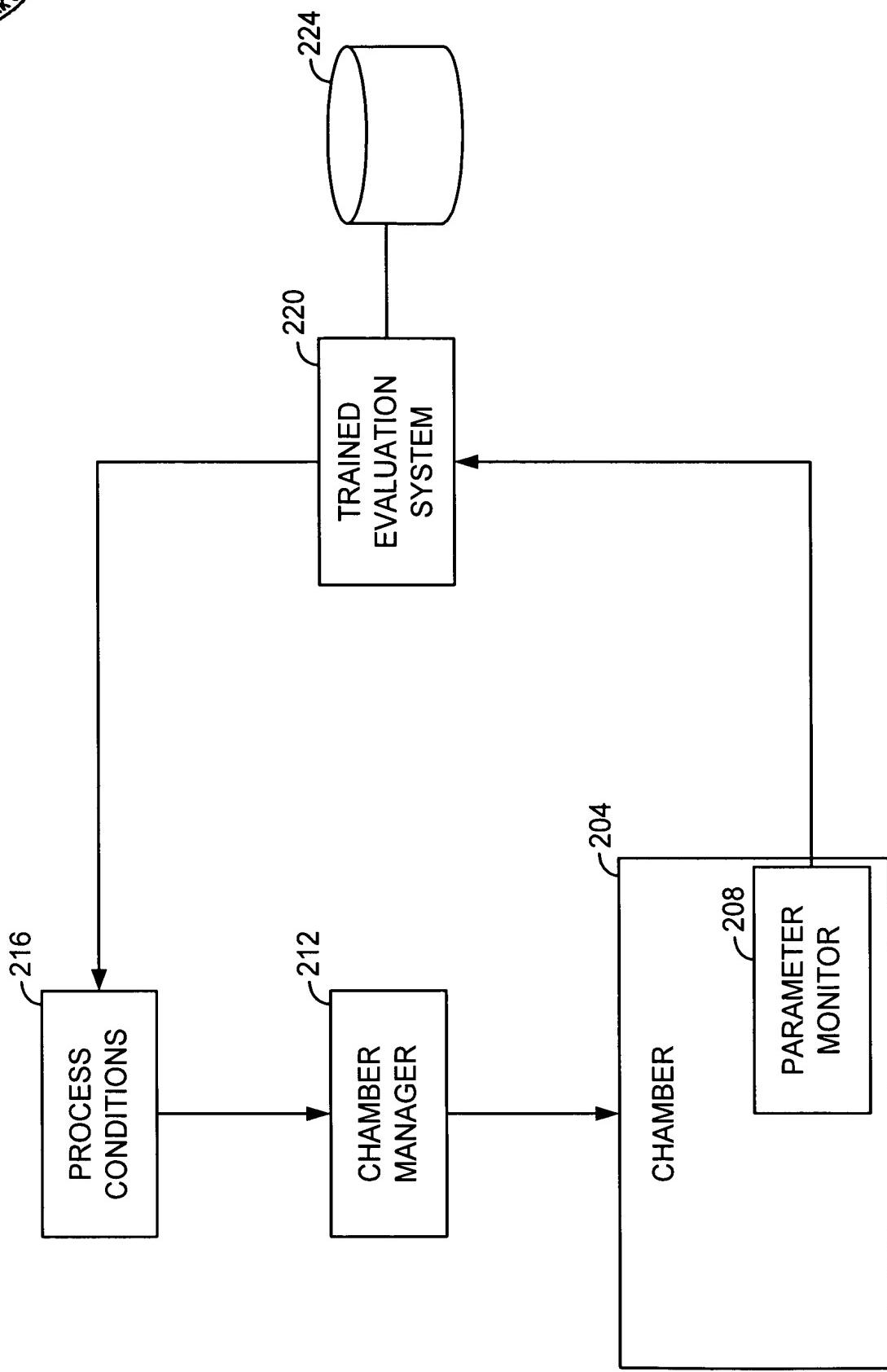


FIG. 2



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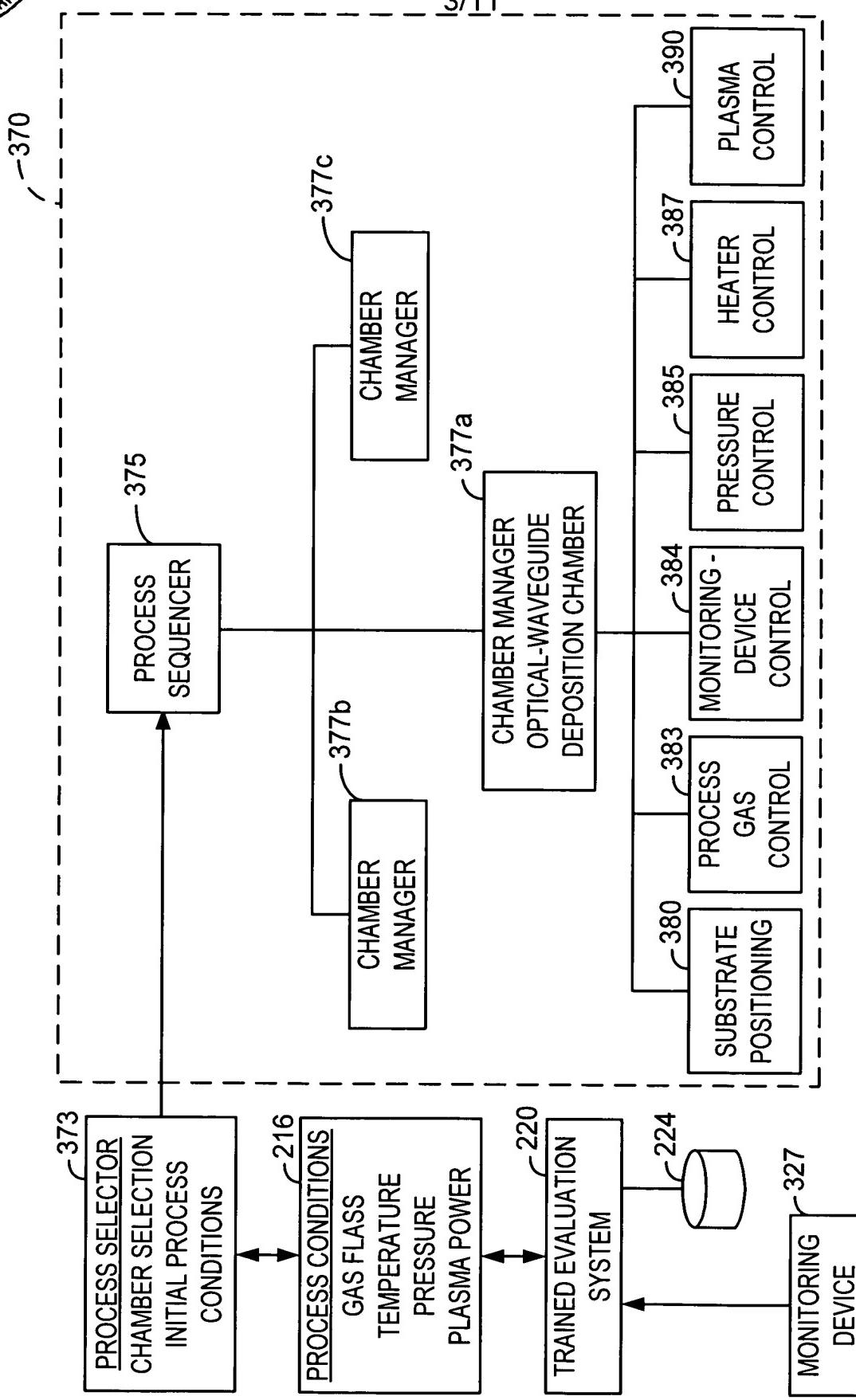


FIG. 3



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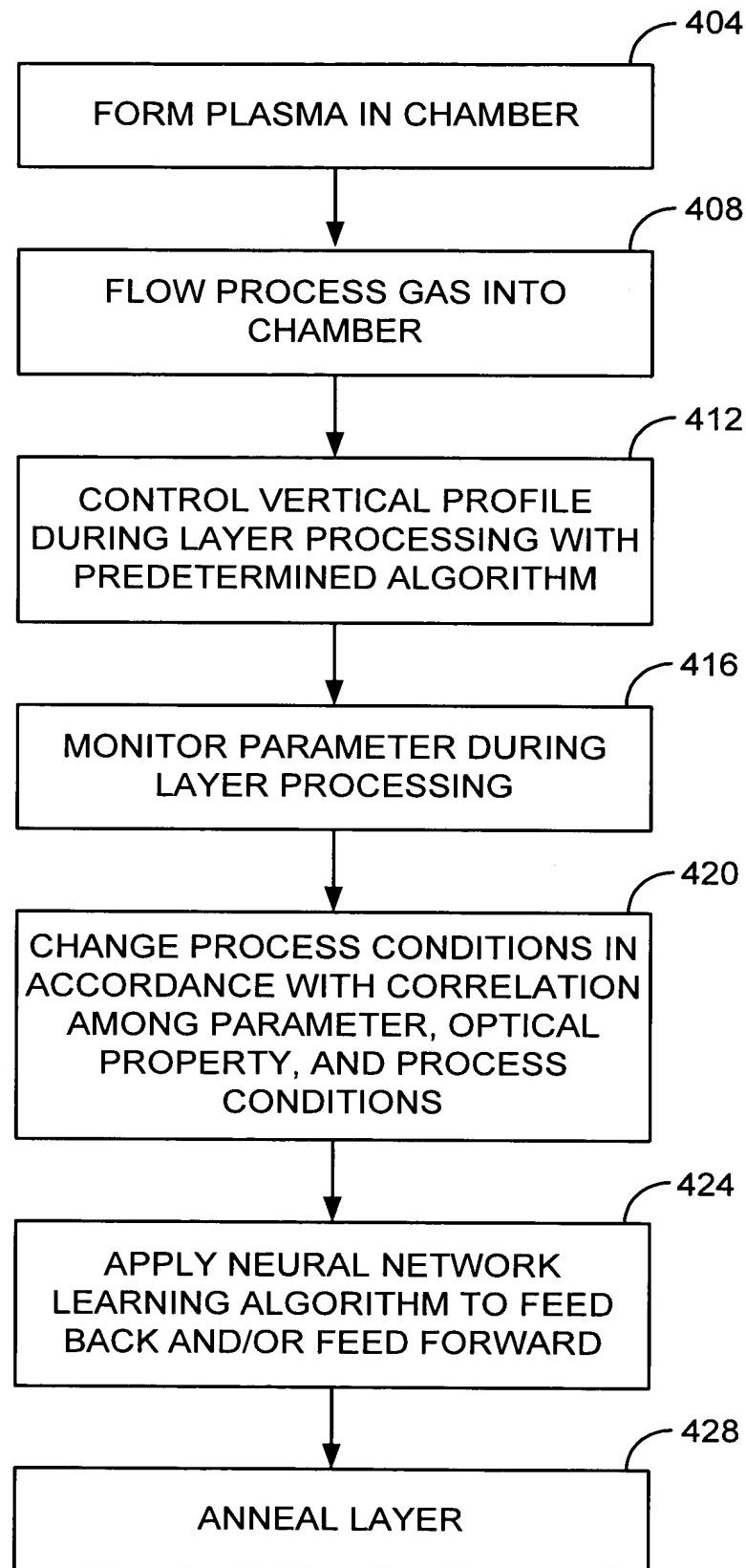


FIG. 4



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USG R.I. vs. USG Film THX

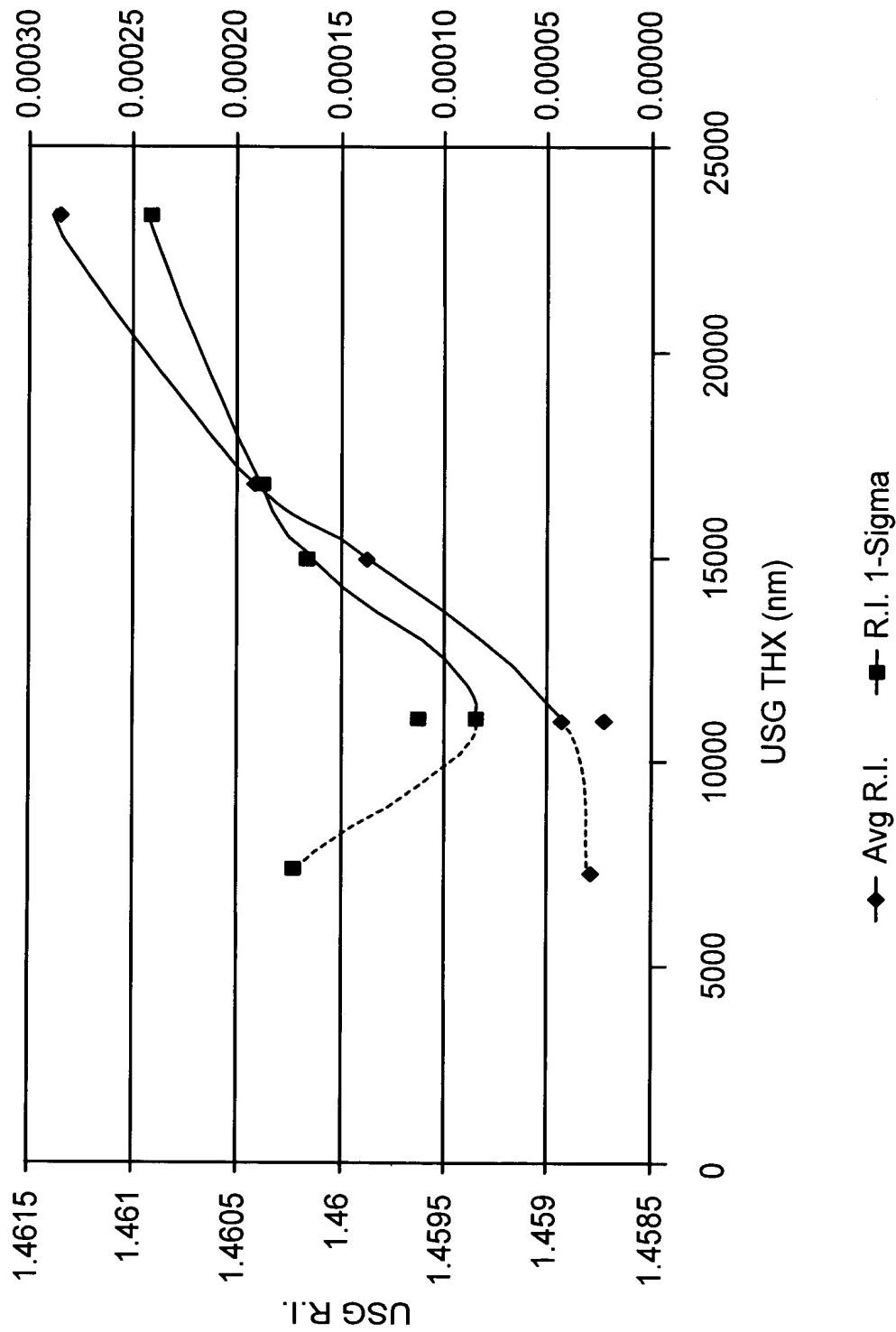


FIG. 5



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USG Dep Rate vs. Dep Time

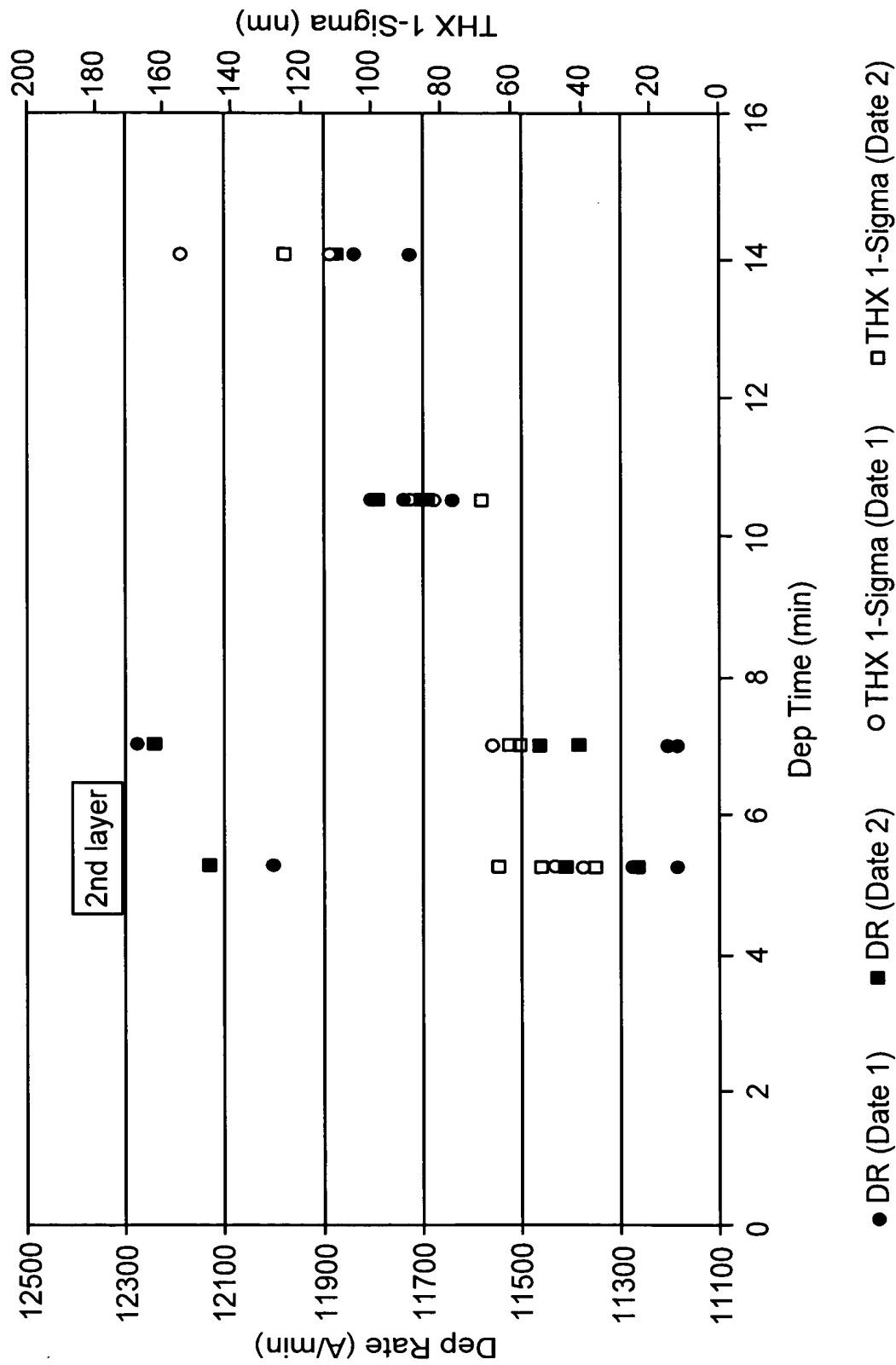


FIG. 6A



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USG R.I. vs. Dep Time

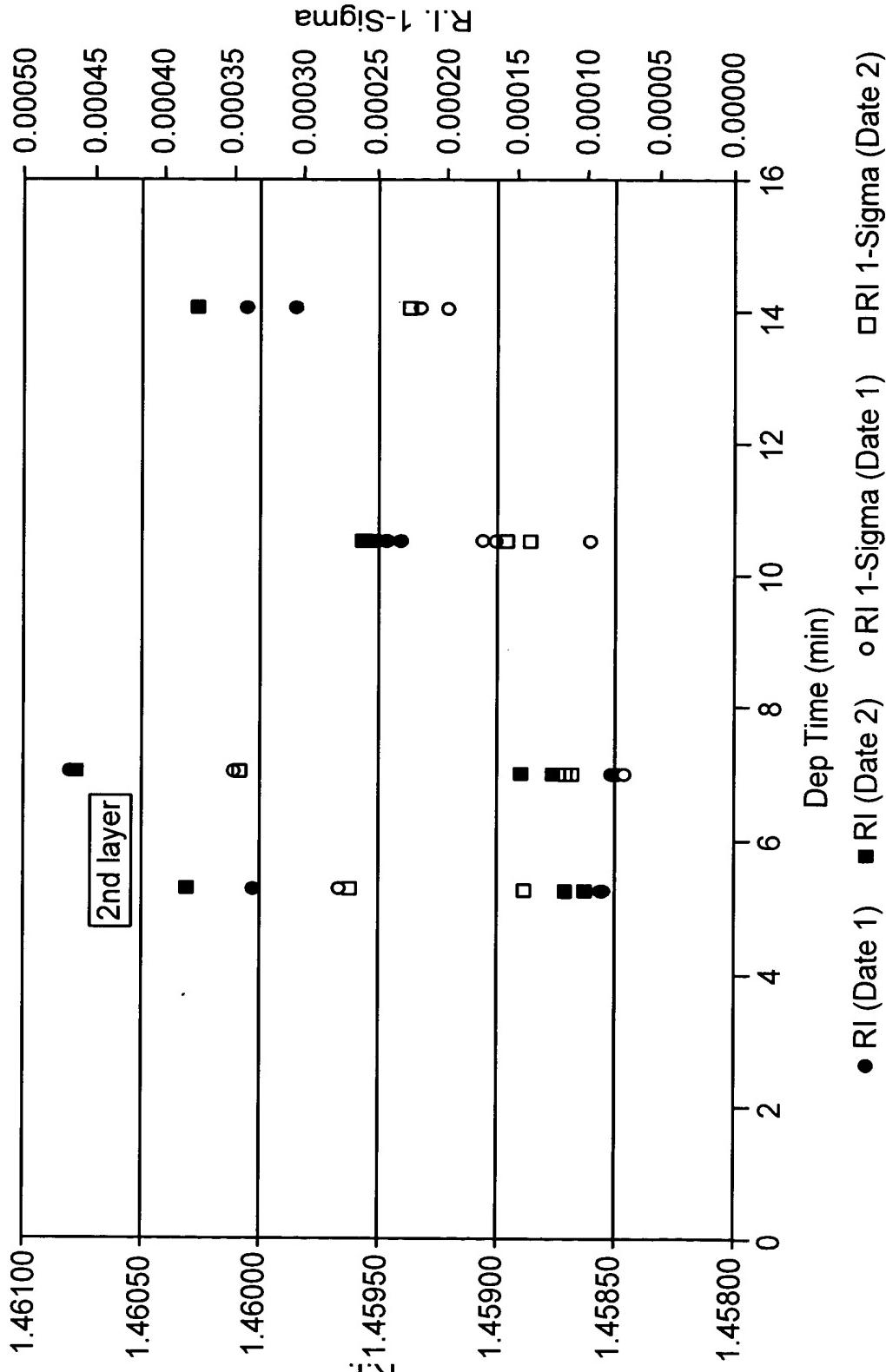


FIG. 6B



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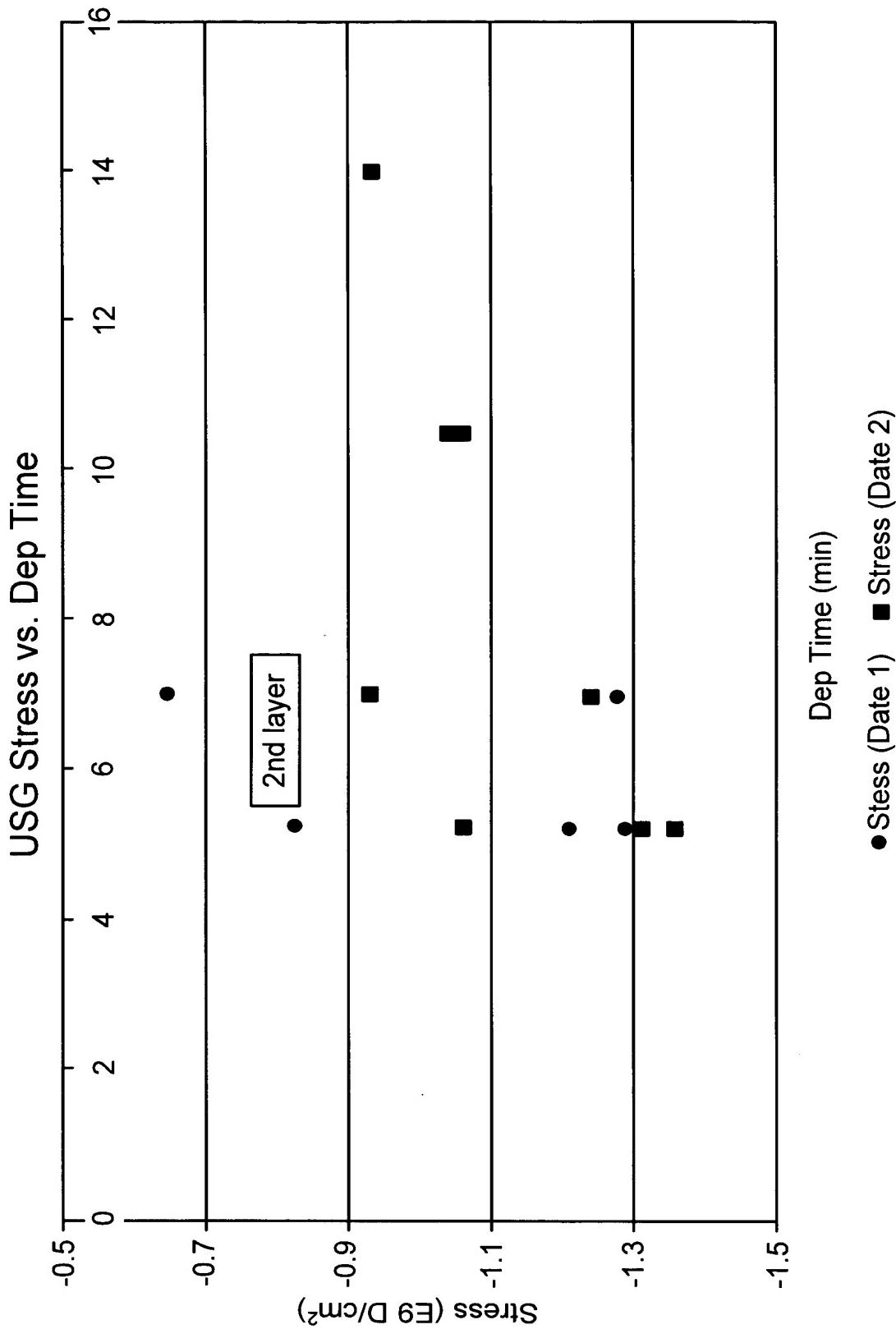


FIG. 6C



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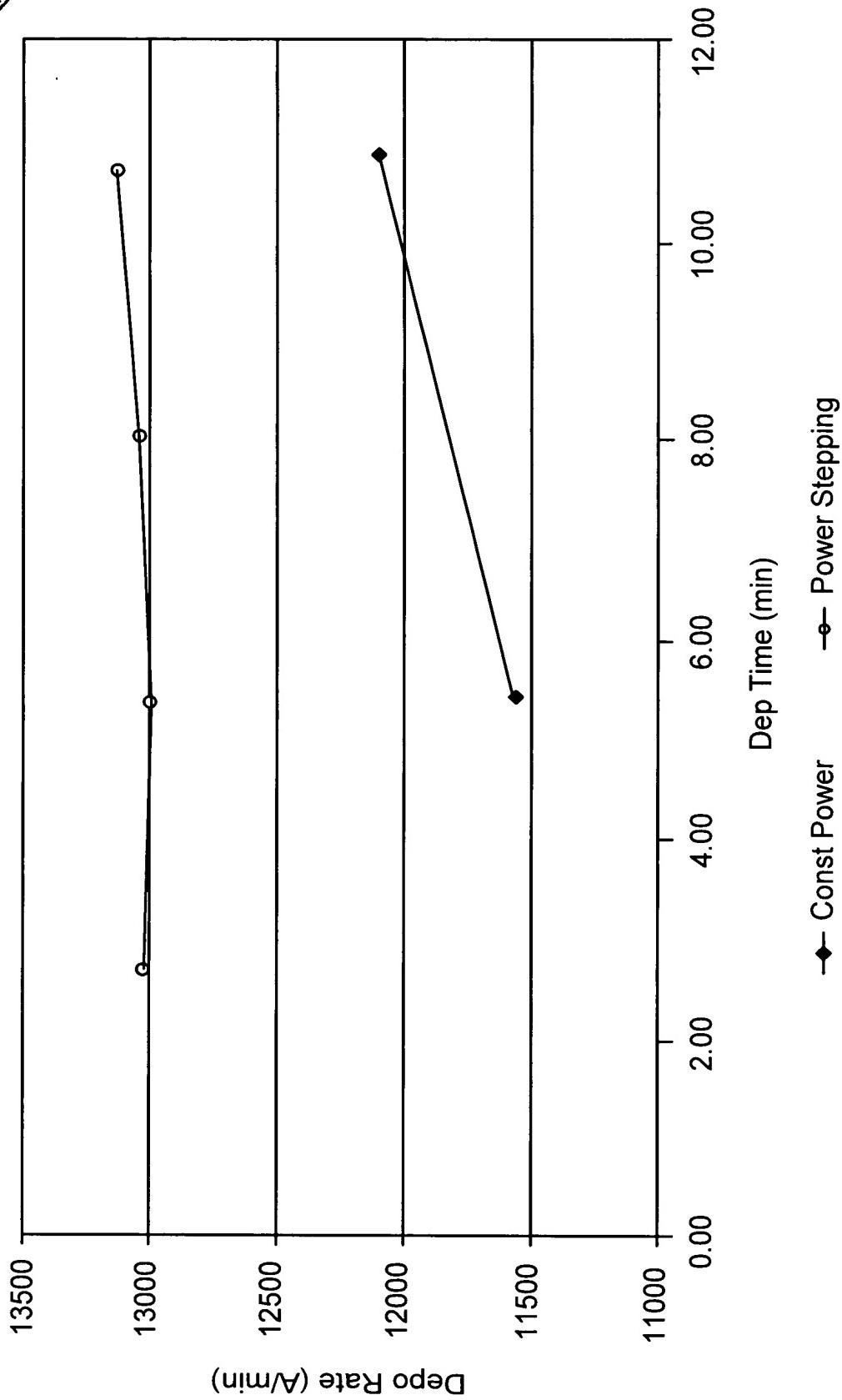


FIG. 7A

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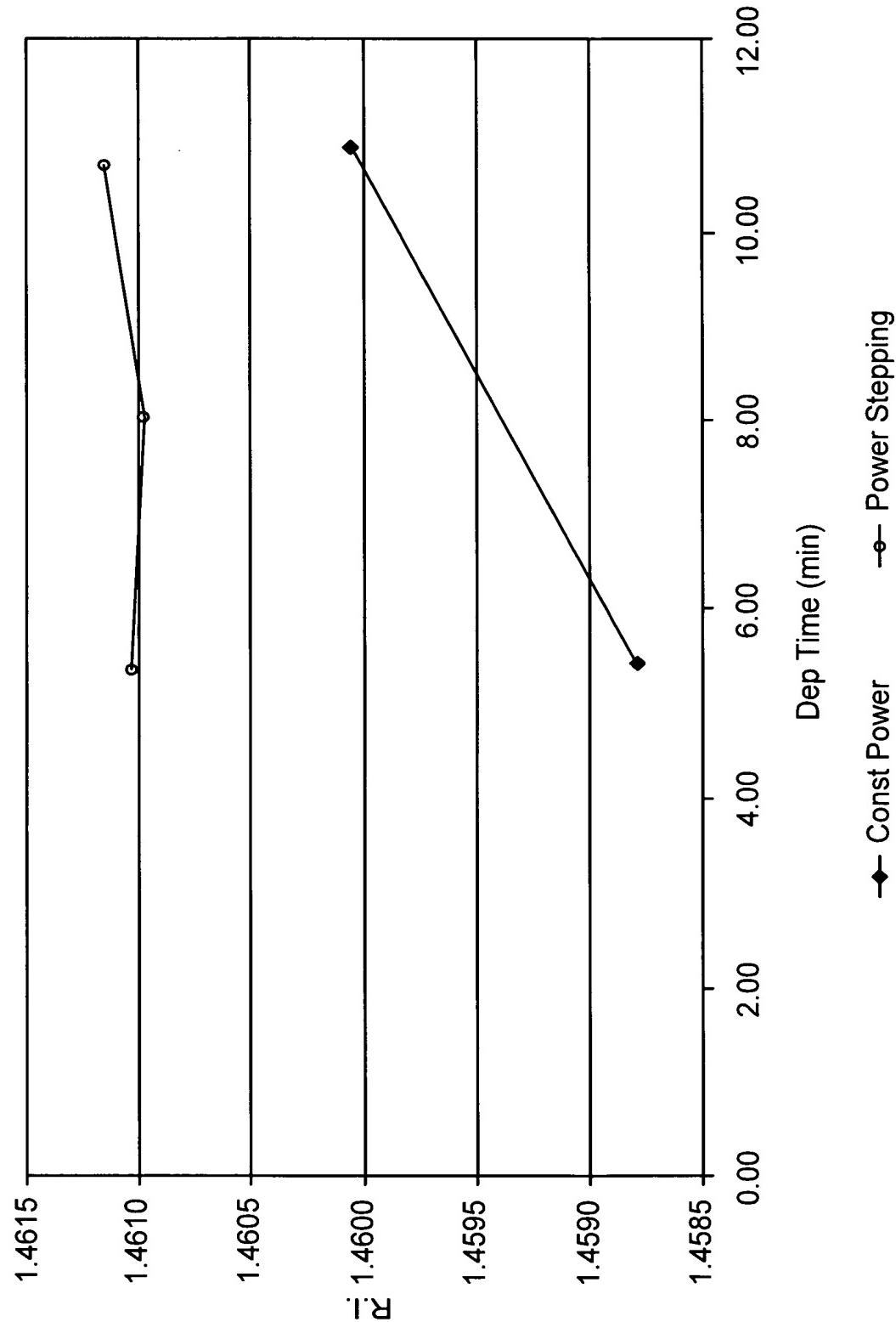


FIG. 7B

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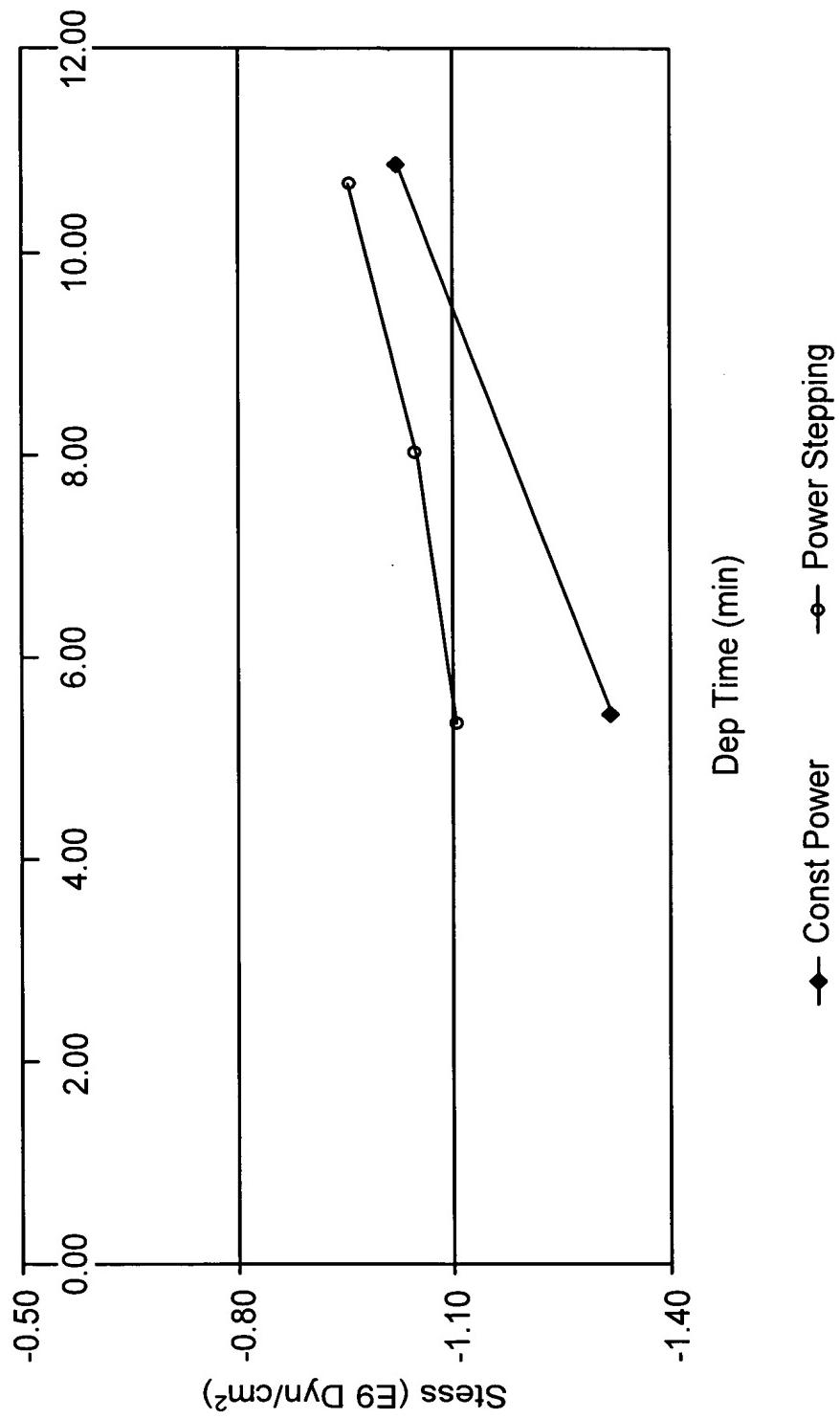


FIG. 7C